

## **AMENDMENTS TO THE CLAIMS**

**Claim 1 (Original)** A nanosize heater-mounted nozzle comprising:  
a nozzle for locally supplying a source gas toward a substrate; and  
a nanosize heater for heating the source gas, located in the vicinity of an opening  
of the nozzle.

**Claim 2 (Original)** The nanosize heater-mounted nozzle according to Claim 1,  
wherein the nanosize heater is composed of carbon nanotube.

**Claim 3 (Currently Amended)** The nanosize heater-mounted nozzle according to  
Claim 1 or 2, wherein the nozzle is formed of an electrically insulating material, and a  
pair of electrodes is located on a side face of the nozzle, and the nanosize heater is  
connected between the electrodes so as to pass over the opening of the nozzle.

**Claim 4 (Original)** The nanosize heater-mounted nozzle according to Claim 3,  
wherein the nozzle is formed of quartz or heat-resistant glass.

**Claim 5 (Original)** The nanosize heater-mounted nozzle according to Claim 3,  
wherein the electrodes are formed of a material having a melting point of 1,700 degree-C  
or higher.

**Claim 6 (Currently Amended)** A method for forming a micro thin film including  
steps of:

positioning the nanosize heater-mounted nozzle, according to Claim one of  
Claims 1 to 5, closely to a surface of a substrate;  
locally supplying a source gas toward the substrate through the nanosize heater-  
mounted nozzle; and  
heating the source gas around an opening of the nozzle while energizing the  
nanosize heater.

**Claim 7 (Original)** A method for manufacturing a nanosize heater-mounted nozzle including steps of:

partially heating a tube formed of an electrically insulating material to shape a tapered nozzle by drawing;

forming a pair of electrodes on a side face of the nozzle; and

connecting a nanosize heater between the electrodes so as to pass over an opening of the nozzle.

**Claim 8 (Original)** The method for manufacturing a nanosize heater-mounted nozzle, according to Claim 7, further including a step of evaporating a conductive portion between the electrodes by supplying a current between the electrodes, after forming the pair of electrodes on the side face of the nozzle.

**Claim 9 (Original)** The method for manufacturing a nanosize heater-mounted nozzle, according to Claim 7, further including a step of irradiating with an electron beam the portion connected between each of the electrodes and the nanosize heater, after connecting the nanosize heater between the electrodes.